

TRADEMARK ASSIGNMENT COVER SHEET

Electronic Version v1.1
Stylesheet Version v1.2

ETAS ID: TM711514

SUBMISSION TYPE:	NEW ASSIGNMENT		
NATURE OF CONVEYANCE:	SECURITY INTEREST		
CONVEYING PARTY DATA			
Name	Formerly	Execution Date	Entity Type
MOVELLA INC.	FORMERLY MCUBE, INC.	02/25/2022	Corporation: DELAWARE
RECEIVING PARTY DATA			
Name:	SILICON VALLEY BANK		
Street Address:	3003 TASMAN DRIVE		
City:	SANTA CLARA		
State/Country:	CALIFORNIA		
Postal Code:	95054		
Entity Type:	Corporation: CALIFORNIA		
PROPERTY NUMBERS Total: 3			
Property Type	Number	Word Mark	
Serial Number:	90663667	MOVELLA	
Registration Number:	4732410	IGYRO	
Registration Number:	4732409	IGYRO	
CORRESPONDENCE DATA			
Fax Number:	4048853900		
<i>Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent using a fax number, if provided; if that is unsuccessful, it will be sent via US Mail.</i>			
Phone:	4048853868		
Email:	rusty.close@troutman.com		
Correspondent Name:	CHRISTOPHER CLOSE		
Address Line 1:	TROUTMAN PEPPER LLP		
Address Line 2:	600 PEACHTREE STREET NE, SUITE 3000		
Address Line 4:	ATLANTA, GEORGIA 30308-2216		
ATTORNEY DOCKET NUMBER:	220763.001345		
NAME OF SUBMITTER:	Christopher C Close, Jr.		
SIGNATURE:	/Christopher C. Close Jr./		
DATE SIGNED:	03/02/2022		
Total Attachments: 11			
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ADDENDUM TO INTELLECTUAL PROPERTY SECURITY AGREEMENT

THIS ADDENDUM TO INTELLECTUAL PROPERTY SECURITY AGREEMENT (this “**Addendum**”) is executed pursuant to, and is an addendum to, that certain Intellectual Property Security Agreement, dated as of June 8, 2020, as the same may be further amended, modified, supplemented or restated from time to time, by and between MOVELLA INC., a Delaware corporation (formerly known as MCUBE, INC.) (“**Assignor**”), and SILICON VALLEY BANK, a California corporation (“**Assignee**”). This Addendum is presented for recordation as constructive notice that Assignor, with its principal office at 2570 N. 1st St., Ste 300, San Jose, CA 95131, the owner of the intellectual property identified in the exhibits attached hereto, has granted to Assignee, with its principal office at 3003 Tasman Drive, Santa Clara, California 95054, a security interest in the intellectual property, and the exclusive rights comprised in the intellectual property, to secure payment of a debt.

IN WITNESS WHEREOF, Assignor has executed this Addendum as of February 25, 2022.

MOVELLA INC.

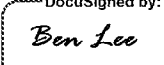
By:  _____
Name: Ben Lee
Title: CEO

EXHIBIT A

Copyrights

Description	Registration Number	Application Number
None Identified		

EXHIBIT B

Patents

No.	Description	Registration/ Application Number	Registration/ Application Date
1.	Multi-Axis MEMS Rate Sensor Device	10,036,635	7/31/2018
2.	MEMS Structure with Improved Shielding and Method	10,046,964	08/14/2018
3.	Integrated Inertial Sensing Device	10,107,625	10/23/2018
4.	Multi-Axis Integrated MEMS Inertial Sensing Device on Single Packaged Chip	10,132,630	11/20/2018
5.	Method to Package Multiple MEMS Sensors and Actuators at Different Gases and Cavity Pressures	10,183,860	01/22/2019
6.	Centrifuge MEMS Stiction Test System and Method	10,317,333	06/11/2019
7.	Integrated MEMS Inertial Sensing Device	10,393,526	08/27/2019

No.	Description	Registration/ Application <u>Number</u>	Registration/ Application <u>Date</u>
8.	Transducer Structure and Method for MEMS Devices	8,477,473	07/02/2013
9.	Method and Structure of an Integrated MEMS Inertial Sensor Device Using Electrostatic Quadrature-Cancellation	9,075,079	07/07/2015
10.	Integrated Inertial Sensing Device	9,612,119	04/04/2017
11.	Wafer Level Centrifuge for MEMS Stiction Detection and Screening System and Method	9,651,473	05/16/2017
12.	Centrifuge MEMS Stiction Detection and Screening System and Method	9,758,374	09/12/2017
13.	MEMS Structure with Improved Shielding and Method	9,950,921	04/24/2018
14.	Apparatus and Methods for Integrated MEMS Devices	10,046,966	08/14/2018
15.	Method to Test the Quality Factor of a MEMS Gyroscope at Chip Probe	10,267,636	04/23/2019

No.	Description	Registration/ Application <u>Number</u>	Registration/ Application <u>Date</u>
16.	Apparatus and Methods for Integrated MEMS Devices	10,479,676	11/19/2019
17.	Ultra-Low Power Sensor for Vibration & Motion Detection	10,982,944	04/20/2021
18.	Method and Structure of an Inertial Sensor Using Tilt Conversion	8,869,616	10/28/2014
19.	Method and Device of MEMS Process Control Monitoring and Packaged MEMS with Different Cavity Pressures	9,249,012	02/02/2016
20.	Methods and Structures of Integrated MEMS-CMOS Devices	9,276,080	03/01/2016
21.	Synchronous Modulation Resonator with Sigma Delta Modulator	9,379,733	06/28/2016
22.	Integrated MEMS Inertial Sensing Device with Automatic Gain Control	9,513,122	12/06/2016
23.	Multi-Axis Integrated Inertial Sensing Device	9,541,396	01/10/2017

No.	Description	Registration/ Application <u>Number</u>	Registration/ Application <u>Date</u>
24.	Method to Package Multiple MEMS Sensors and Actuators at Different Gases and Cavity Pressures	9,725,304	08/08/2017
25.	Methods and Structures of Integrated MEMS-CMOS Devices	9,950,924	04/24/2018
26.	Multiple MEMS Device and Methods	PCT US2017019766	02/27/2017
27.	Apparatus and Methods for Integrated MEMS Devices	PCT US2017025992	04/04/2017
28.	Transducer Structure and Method for MEMS Devices	9,377,487	06/28/2016
29.	Methods and Apparatus for Mobile Device Event Detection	15/368,514	12/02/2016
30.	Method and Device of MEMS Process Control Monitoring and Packaged MEMS with Different Cavity Pressures	10,343,896	07/09/2019
31.	Apparatus and Method for Integrated MEMS Devices (China)	201780034773.3	04/04/2017

No.	Description	Registration/ Application <u>Number</u>	Registration/ Application <u>Date</u>
32.	Methods and Structures of Integrated MEMS-CMOS Devices (China)	CN106698330	03/29/2019
33.	Power Saving Method of Operating Portable Computing Device (China)	201410374656.X	07/31/2014
34.	Method and Structure of an Integrated MEMS Inertial Sensor Devices Using Electrostatic Quadrature-Cancellation (EP)	14171673	06/09/2014
35.	Multi-Axis Integrated MEMS Inertial Sensing Device on Single Packaged Chip (EP)	2759802	01/02/2019
36.	System on a Chip Using Integrated MEMS and CMOS Devices (China)	CN202717577	02/06/2013
37.	Dynamic Offset Calibration (China)	CN103246366	11/14/2017
38.	Methods and Structures of Integrated MEMS-CMOS Devices (China)	CN103303859	01/18/2017

No.	Description	Registration/ Application <u>Number</u>	Registration/ Application <u>Date</u>
39.	Methods and Structures of Integrated MEMS-CMOS Devices (Taiwan)	TWI525792	03/11/2016
40.	Methods and Structures of Integrated MEMS-CMOS Devices (Taiwan)	TWI601268	10/01/2017
41.	Methods and Structures of Integrated MEMS-CMOS Devices (Taiwan)	TWI654738	03/21/2019
42.	Integrated Inertial Sensing Device and System Including the Same (Taiwan)	TWI506246	11/01/2015
43.	Multi-Axis MEMS Rate Sensor Device (Taiwan)	TWI606229	11/21/2017
	Multi-Axis MEMS Inertial Sensing Device on Single Packaged Chip (Taiwan)	TWI518302	01/21/2016
44.	Centrifuge MEMS Stiction Detection and Screening System and Method (China)	201410117025	
45.	MEMS-Based Proximity Sensor Device and Method (Taiwan)	TWI509502	11/21/2015

No.	Description	Registration/ Application <u>Number</u>	Registration/ Application <u>Date</u>
46.	MEMS-Based Proximity Sensor Device and Method (China)	CN104219346	12/01/2017
47.	A MEMS Structure with Improved Shielding and Method (Taiwan)	TWI579229	04/21/2017
48.	Method and Structure of Monolithically Integrated Absolute Pressure Sensor (Taiwan)	TWI528566	04/01/2016

EXHIBIT C

Trademarks

No.	Description	Registration/Serial Number	Registration/ Application Date
1.	MOVELLA	90/663,667	04/22/2021
2.	IGYRO	4,732,410	05/05/2015
3.	IGYRO	4,732,409	05/05/2015
4.	MOVELLA (Canada)	2139715	04/27/2021
5.	MOVELLA (International)	1618617	04/27/2021
6.	SENSFIT (United Kingdom)	918173087	06/16/2020
7.	SENSFIT (EU)	018173087	06/18/2020

No.	Description	Registration/ Serial Number	Registration/ Application Date
8.	MOVELLA (Australia)	2218566	04/27/2021
9.	VGYRO (China)	12780832	10/28/2014
10.	MOVELLA (Taiwan)	110033208	05/11/2021